

ABSTRACT OF THE DISCLOSURE

A substrate-processing system has several processing units, a loading/unloading section for transferring wafers to be processed to each unit and taking out processed wafers from each unit and a sub-arm mechanism for receiving/transferring the substrates from/to the loading/unloading section and transferring the substrates one by one to each unit. The processing units and the sub-arm mechanism are controlled by a controller so that each unit processes the substrates one by one in accordance with a one-cycle time that is the maximum period among periods  $t_1/m$  to  $t_n/m$  obtained by dividing periods  $t_1$  to  $t_n$  by the number "m" of identical units of each processing unit. The controller sets a pre-waiting time (before processing) for each processing unit.